



Docket No. 740756-2709

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Koichiro TANAKA) Group Art Unit: 1725
Application No. 10/769,820) Examiner: Samuel Heinrich
Filed: February 3, 2004) Confirmation No. 9528
For: LASER IRRADIATION STAGE, LASER)
IRRADIATION OPTICAL SYSTEM, LASER
IRRADIATION APPARATUS, LASER
IRRADIATION METHOD, AND METHOD OF...

REQUEST FOR RESTRICTION RESPONSE

Mail Stop **AMENDMENT**
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Request for Restriction Response mailed April 18, 2005, Applicant responds as follows: